



THIN FILM PZT PIEZO MEMS FOR MICRO-ROBOTIC ANGULAR RATE SENSING AND ROTARY ACTUATION



**Gabriel Smith, Ryan Rudy, Don DeVoe, Sarah Bedair,
William Nothwang, Jeffrey Pulskamp, Luz Sanchez,
Rob Proie, Vishnu Ganesan, Joe Conroy, and Ron Polcawich**

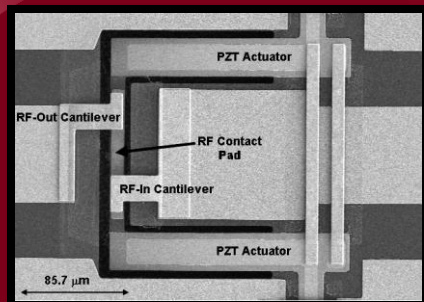
July 31, 2012
U.S. Army Research Laboratory

Approved for Public Release

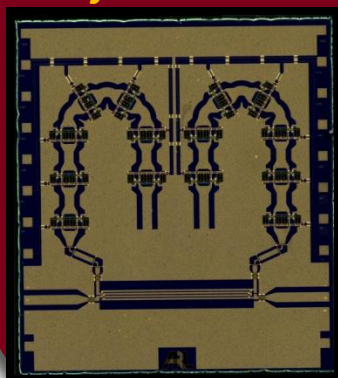
Report Documentation Page				Form Approved OMB No. 0704-0188	
Public reporting burden for the collection of information is estimated to average 1 hour per response, including the time for reviewing instructions, searching existing data sources, gathering and maintaining the data needed, and completing and reviewing the collection of information. Send comments regarding this burden estimate or any other aspect of this collection of information, including suggestions for reducing this burden, to Washington Headquarters Services, Directorate for Information Operations and Reports, 1215 Jefferson Davis Highway, Suite 1204, Arlington VA 22202-4302. Respondents should be aware that notwithstanding any other provision of law, no person shall be subject to a penalty for failing to comply with a collection of information if it does not display a currently valid OMB control number.					
1. REPORT DATE 31 JUL 2012		2. REPORT TYPE		3. DATES COVERED 00-00-2012 to 00-00-2012	
4. TITLE AND SUBTITLE Thin Film PZT Piezo Mems for Micro-Robotic Angular Rate Sensing and Rotary Actuation				5a. CONTRACT NUMBER	
				5b. GRANT NUMBER	
				5c. PROGRAM ELEMENT NUMBER	
6. AUTHOR(S)				5d. PROJECT NUMBER	
				5e. TASK NUMBER	
				5f. WORK UNIT NUMBER	
7. PERFORMING ORGANIZATION NAME(S) AND ADDRESS(ES) U.S. Army Research Laboratory, 2800 Powder Mill Road, Adelphi, MD, 20783-1197				8. PERFORMING ORGANIZATION REPORT NUMBER	
9. SPONSORING/MONITORING AGENCY NAME(S) AND ADDRESS(ES)				10. SPONSOR/MONITOR'S ACRONYM(S)	
				11. SPONSOR/MONITOR'S REPORT NUMBER(S)	
12. DISTRIBUTION/AVAILABILITY STATEMENT Approved for public release; distribution unlimited					
13. SUPPLEMENTARY NOTES Presented at the 2nd Multifunctional Materials for Defense Workshop in conjunction with the 2012 Annual Grantees'/Contractors' Meeting for AFOSR Program on Mechanics of Multifunctional Materials & Microsystems Held 30 July - 3 August 2012 in Arlington, VA. Sponsored by AFRL, AFOSR, ARO, NRL, ONR, and ARL.					
14. ABSTRACT					
15. SUBJECT TERMS					
16. SECURITY CLASSIFICATION OF:			17. LIMITATION OF ABSTRACT Same as Report (SAR)	18. NUMBER OF PAGES 27	19a. NAME OF RESPONSIBLE PERSON
a. REPORT unclassified	b. ABSTRACT unclassified	c. THIS PAGE unclassified			

RF MEMS

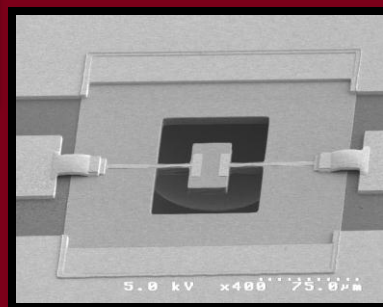
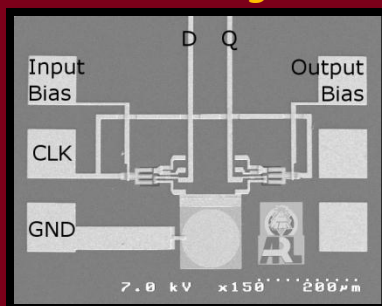
Switches



MEMS Phase Shifters

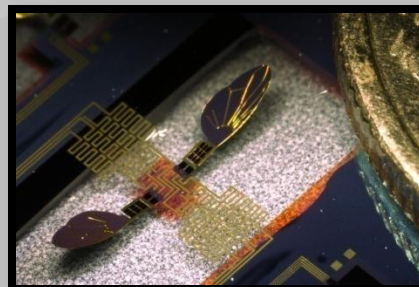


Mechanical Logic

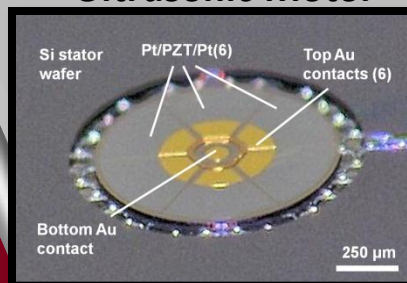


Resonators, Filters, & Transformers

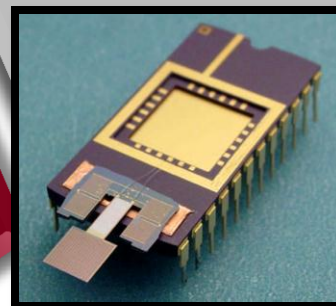
Micro-flight



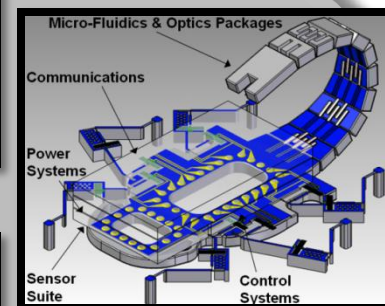
Ultrasonic Motor



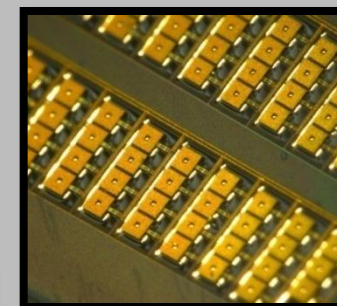
Piezoelectric Energy Harvesting



Terrestrial



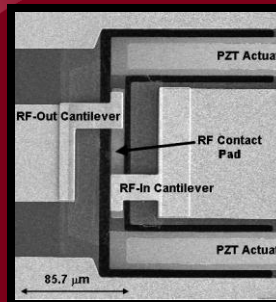
Bio-Inspired Adhesives



MM-SCALE ROBOTICS

**RF
MEMS**

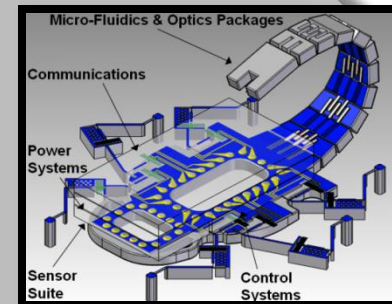
Switches



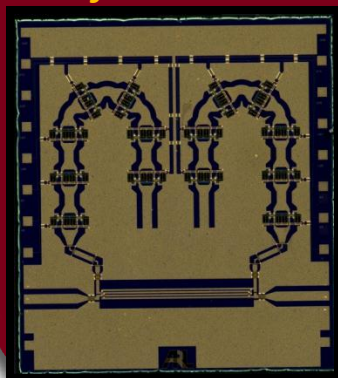
Angular rate
sensors for stable
microflight control

Micro-flight

Terrestrial



**MEMS Phase
Shifters**

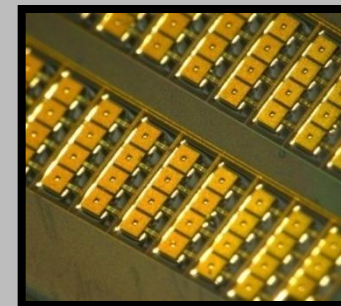


Mechanical

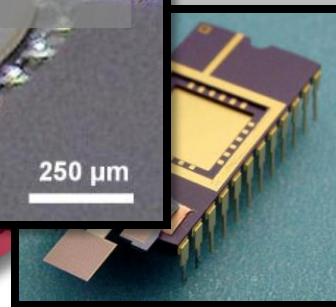


Thinfilm traveling
wave motors

Bio-Inspired Adhesives



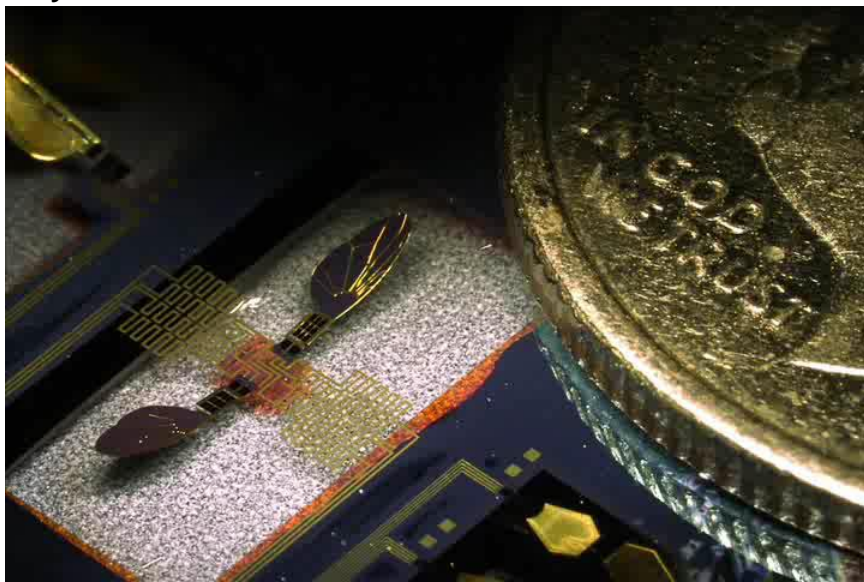
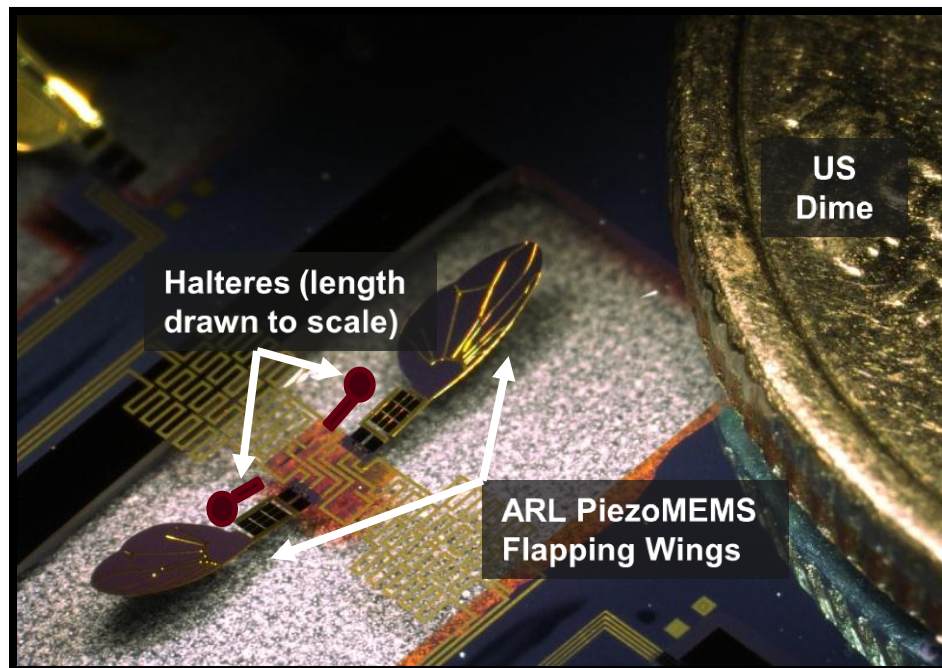
Energy



**MM-SCALE
ROBOTICS**

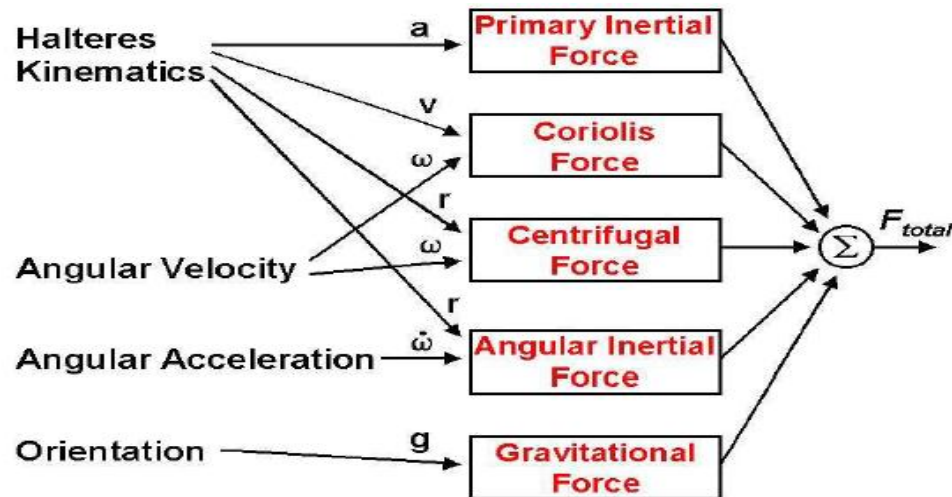
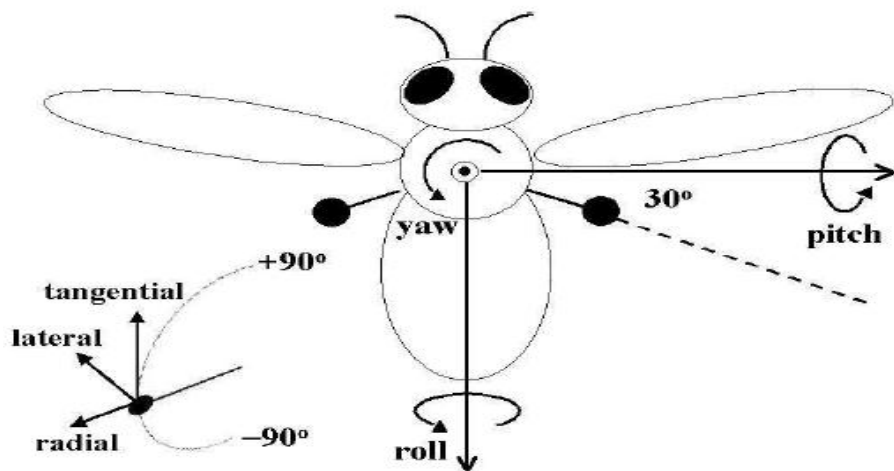


Fly Video: M. Dickinson Caltech



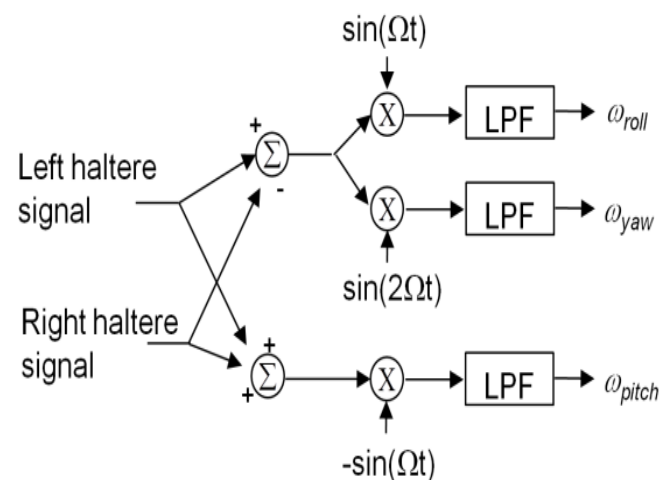
Angular rate sensing on 1-30 mg platform

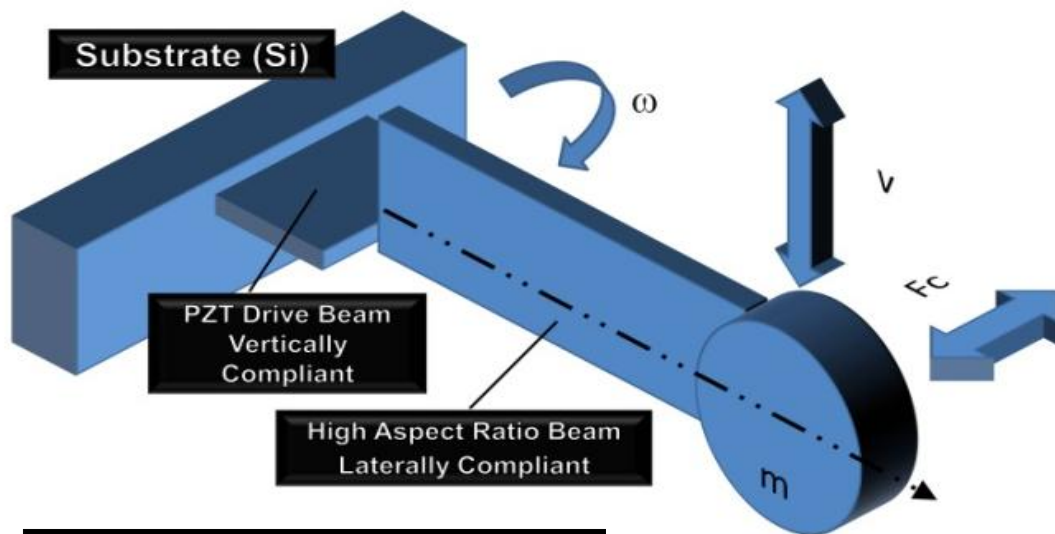
- 2 orders smaller than packaged state of the art gyroscope.
- Integrated biomimetic PZT actuator/sensor approach.
- Haltere-like sensor



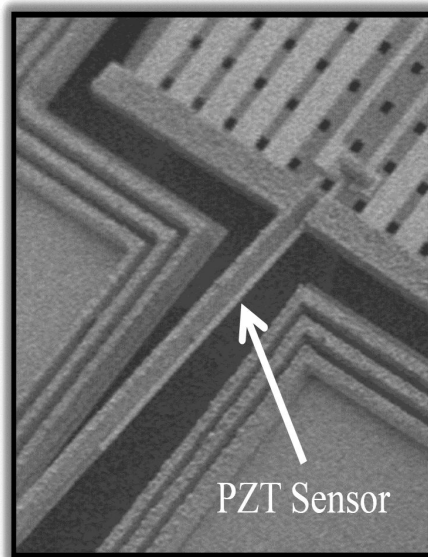
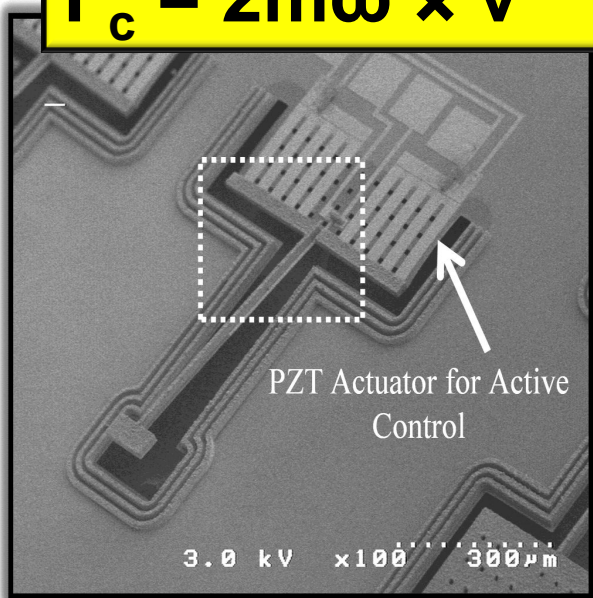
Equation of Motion for macro haltere by Wu et al.

$$\begin{aligned} \ddot{\theta} + 2\zeta\omega_n\dot{\theta} + \omega_n^2\theta = & \dot{\Omega}_3 \sin(\gamma) - \dot{\Omega}_1 \cos(\gamma) - \dot{\gamma}^2 \cos(\theta) \sin(\theta) \\ & + 2\dot{\gamma}[(\Omega_3 \cos(\gamma) + \Omega_1 \sin(\gamma)) \cos^2(\theta) - \Omega_2 \cos(\theta) \sin(\theta)] \\ & + (\Omega_3^2 \cos^2(\gamma) + \Omega_1^2 \sin^2(\gamma) - \Omega_2^2) \cos(\theta) \sin(\theta) \\ & + (\Omega_2\Omega_3 \cos(\gamma) + \Omega_1\Omega_2 \sin(\gamma)) \cos(2\theta) + 2\Omega_1\Omega_3 \cos(\theta) \sin(\theta) \cos(\gamma) \sin(\gamma) \end{aligned}$$





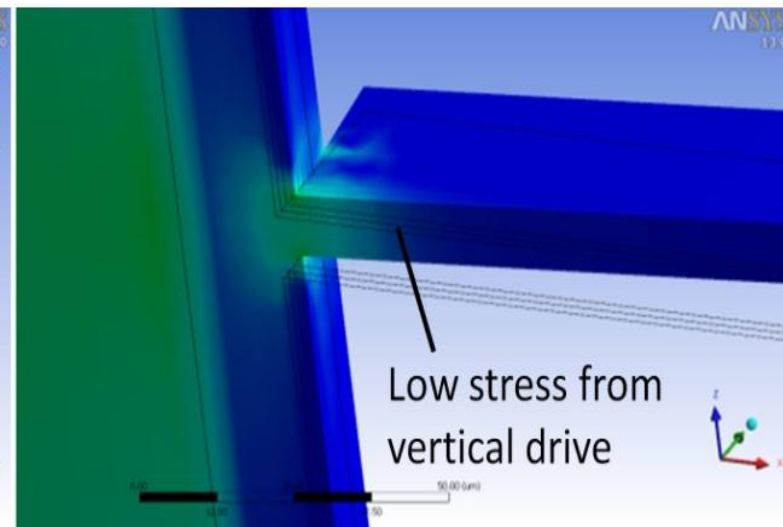
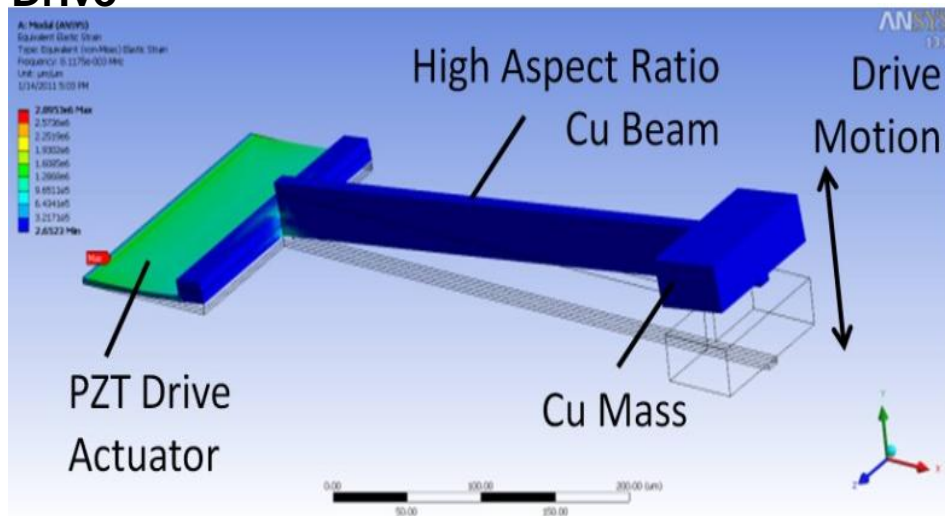
$$F_c = 2m\omega \times v$$



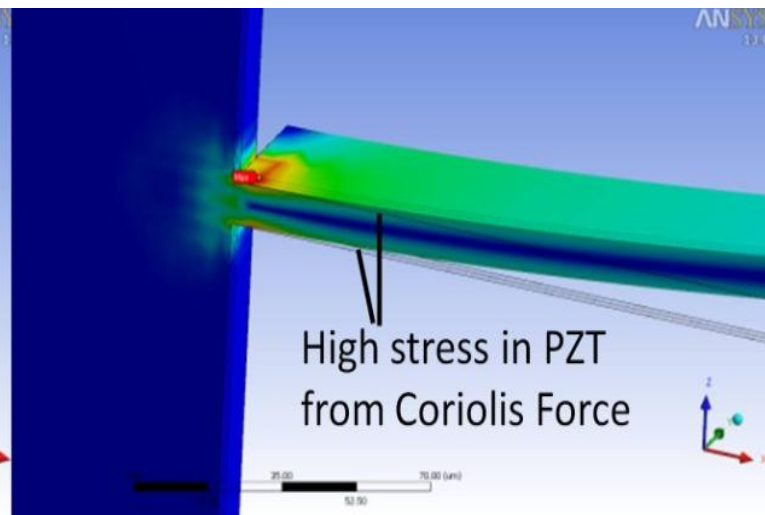
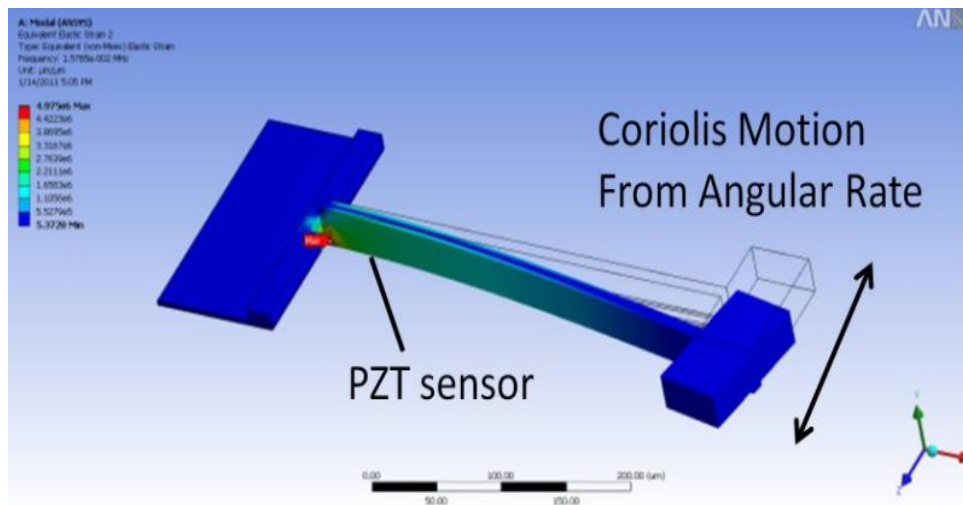
Fundamental Challenges:

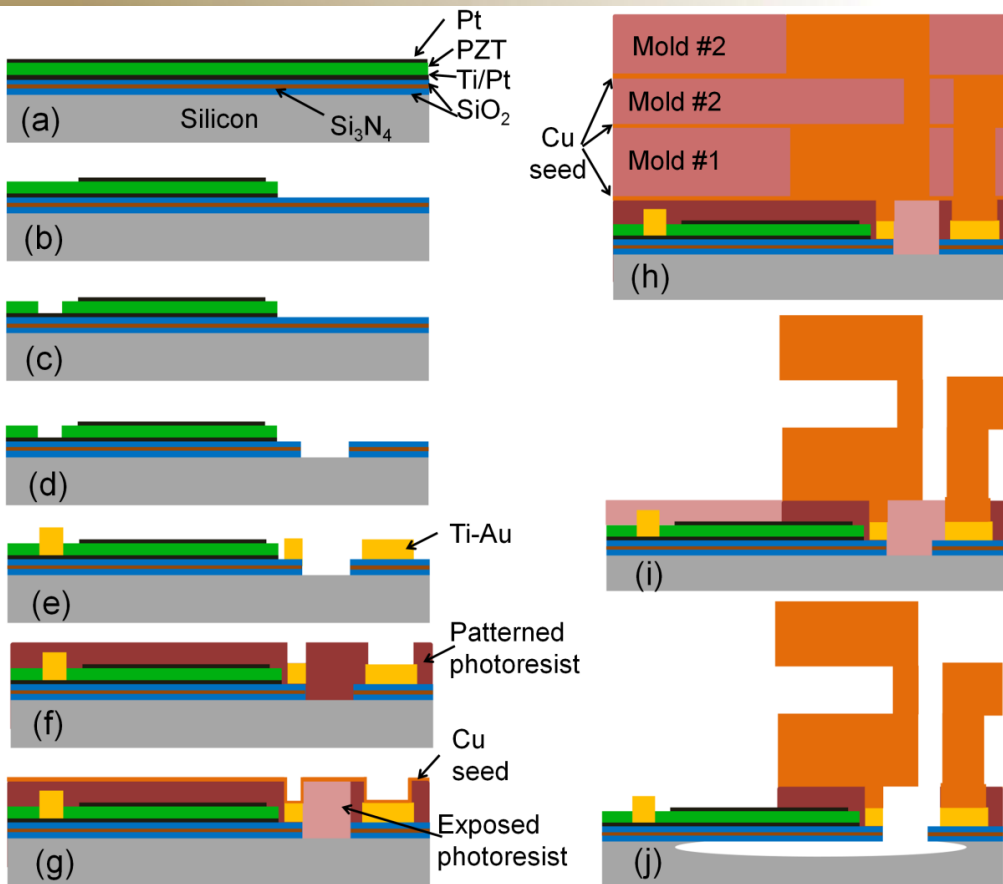
- **Body Vibrations**
 - Raise Frequency of sensor structure above wing beat
 - **Complex Forces on 3 axes**
 - Oscillate the Haltere to extract the ang. rate components
 - **Axis Isolation**
 - Couple the 2 Haltere electrical signals
 - Decouple the rate information for 3 axis
 - **Low Q**
 - Trade size, weight, power for sensitivity
- Approved for Public Release

Drive

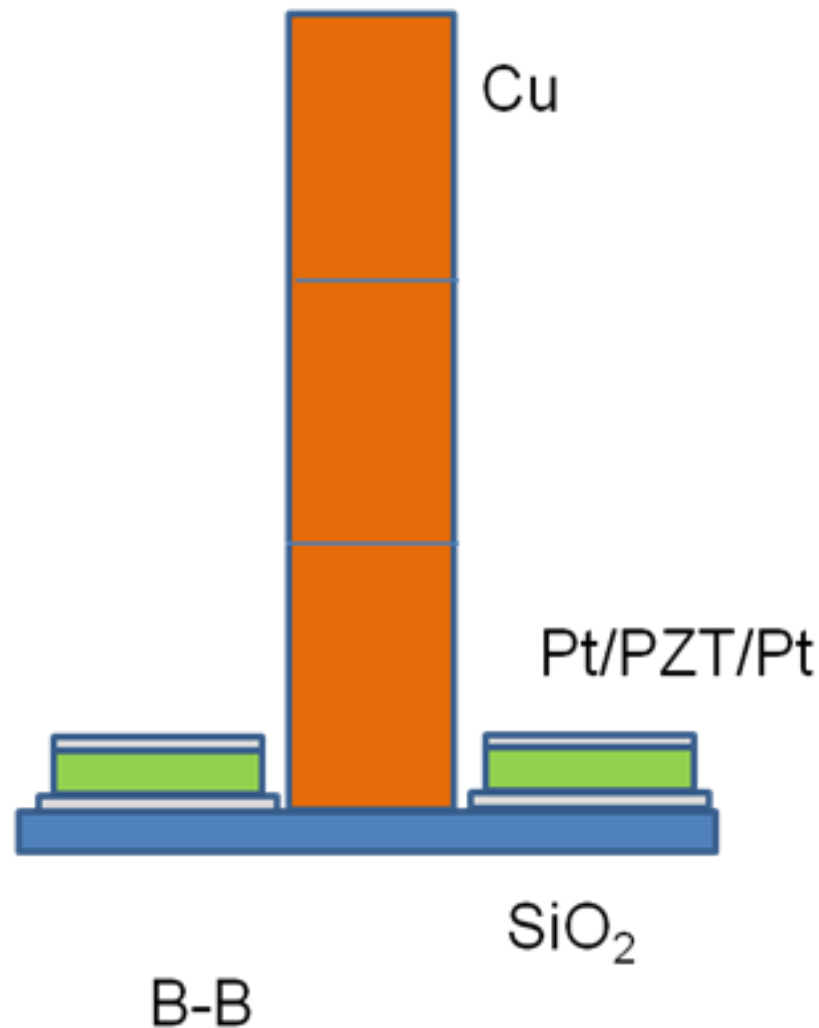


Sense





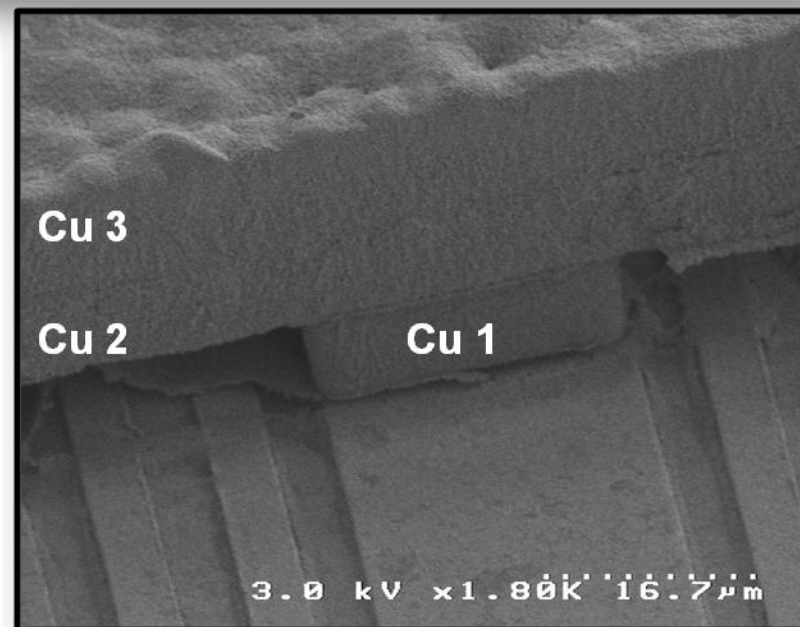
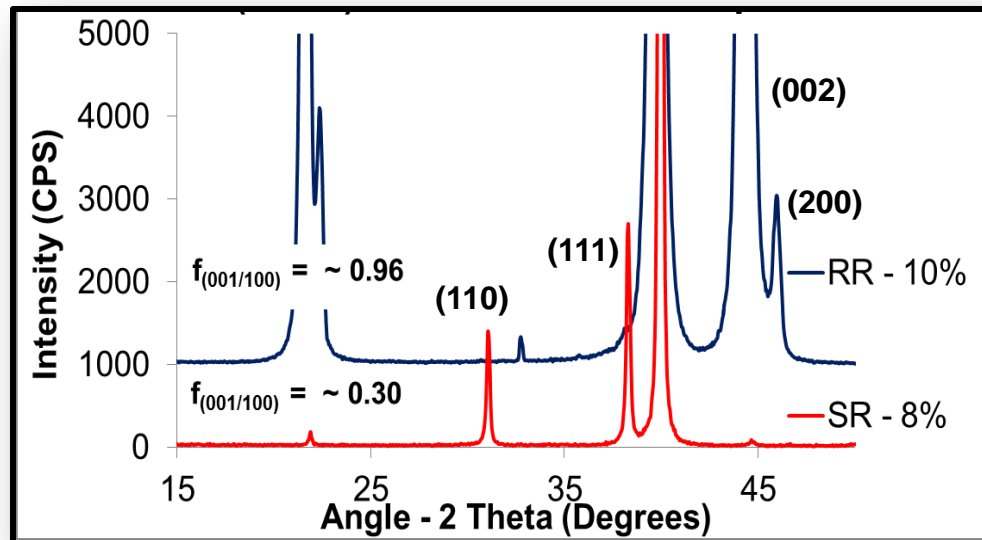
Material	Nominal Thickness
Cu	10-30 μm
Top Pt	1000Å
PZT	1 μm
Bottom Pt	1000Å
SiO ₂	2 μm



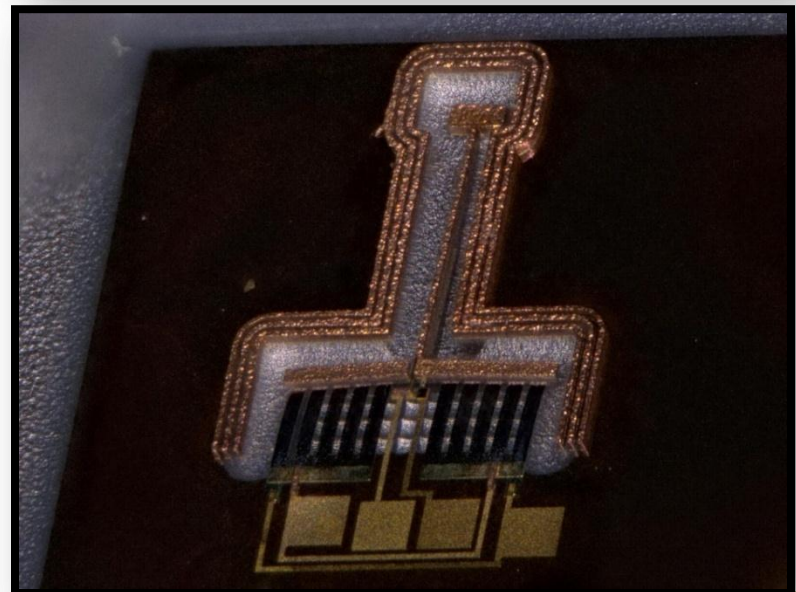
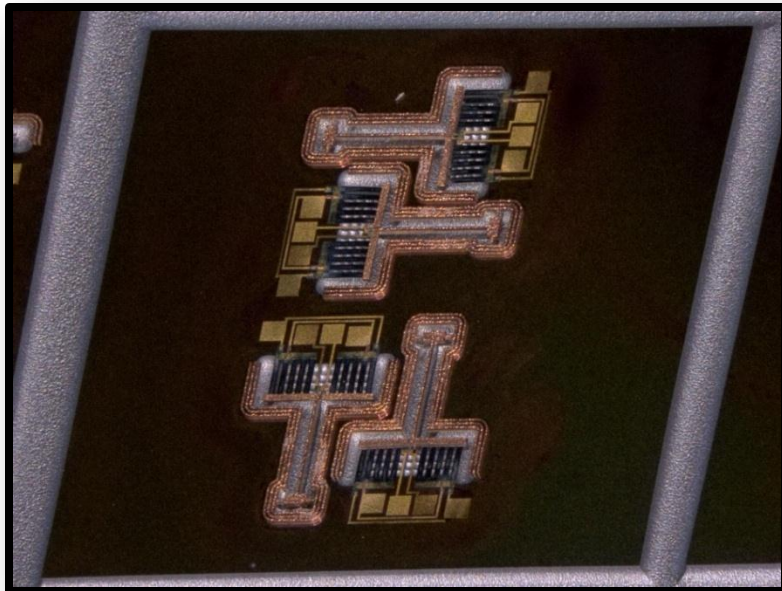
Collaboration with Chris Meyer (ARL)

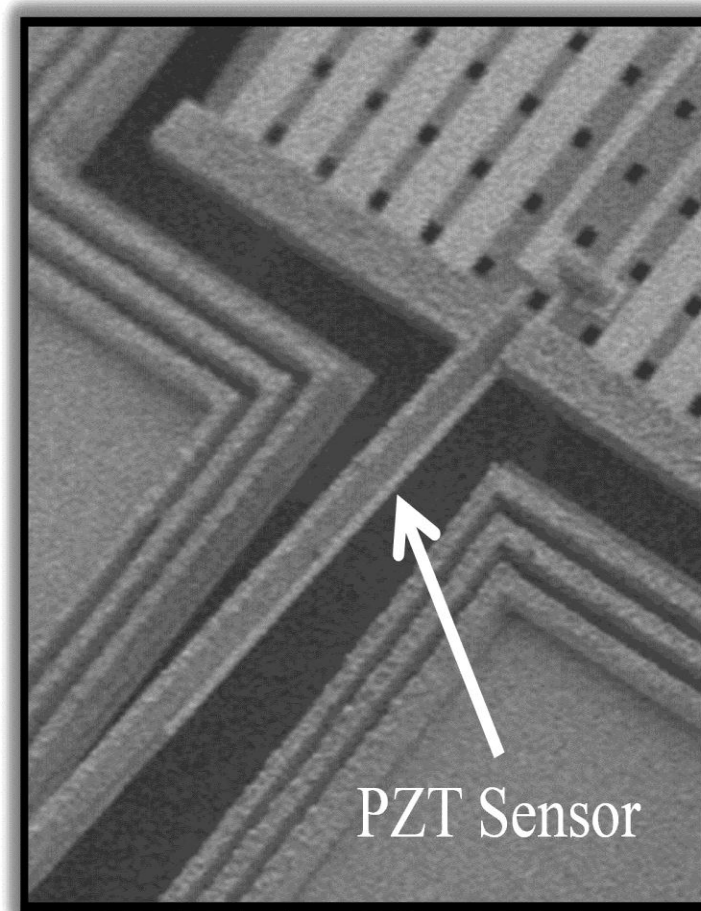
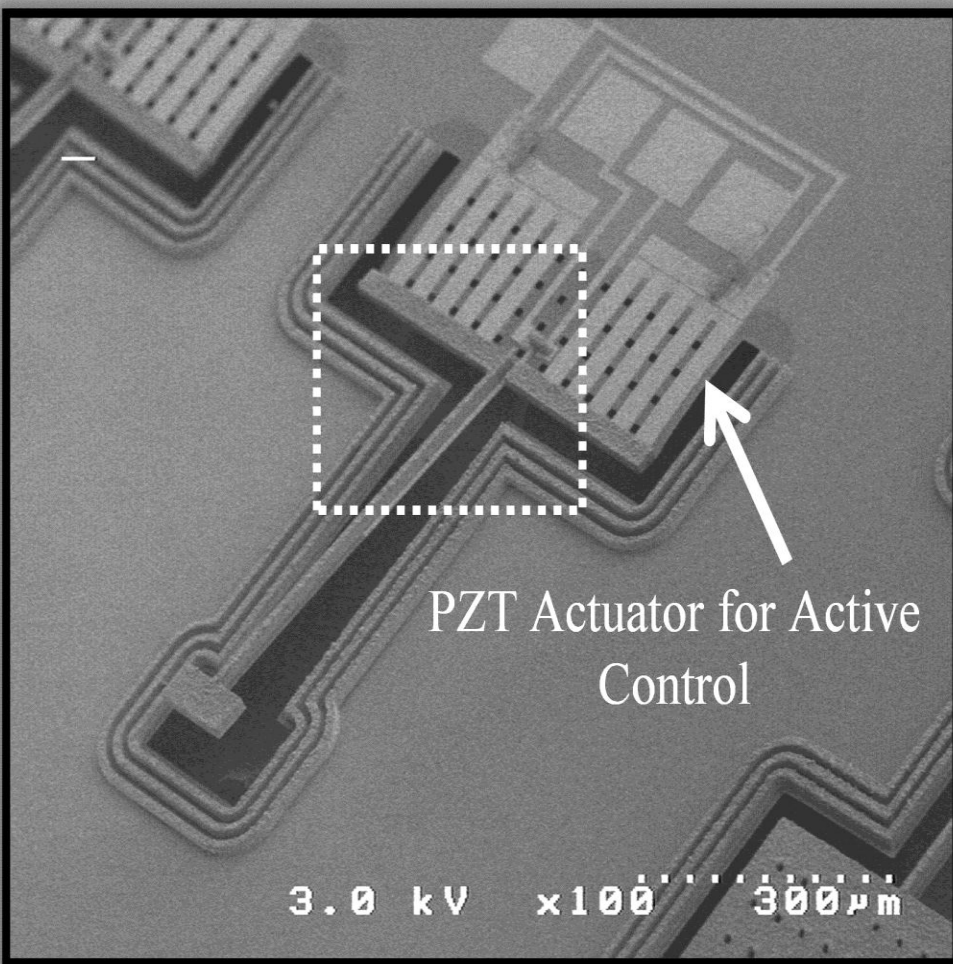
Approved for Public Release

- PZT (52/48) thin films
 - Deposited by chemical solution deposition with 10% Pb excess
 - Pt template (111) with a FWHM of 2 deg
 - (001) PZT with a Lotgering Factor > 0.95
- Pt & PZT Patterning → Ion-mill configured with SIMS endpoint detection
- Multilayer Cu Process → 3 layers
 - Electroplated Cu
 - Photoresist Molds
 - Wet release process for molds
- Final Release
 - Isotropic XeF_2 etch of exposed Si



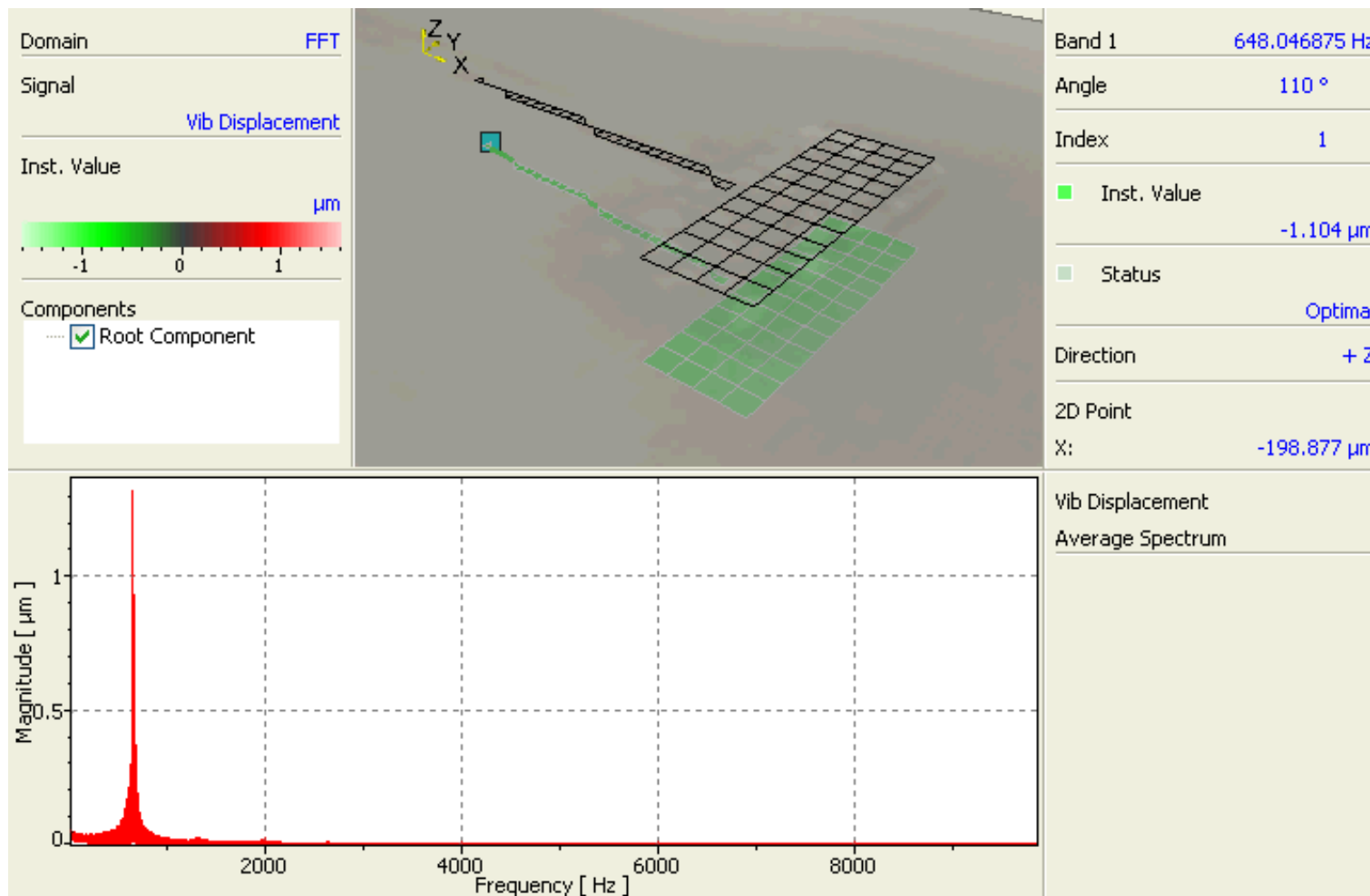
- Length & Size Variances
- Individual Devices
- 2-axis sensing



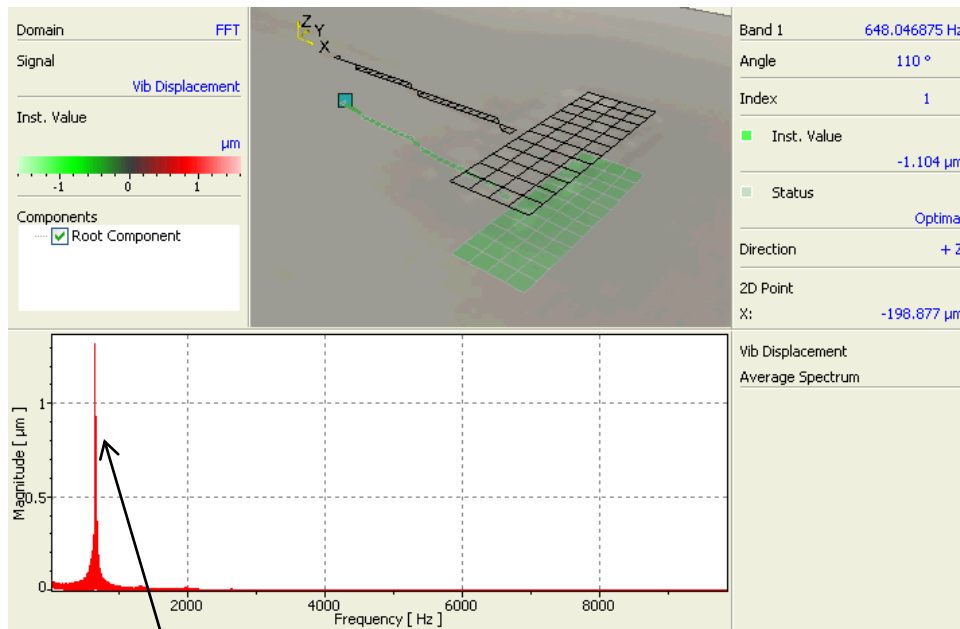


SEM of a PZT-based MEMS haltere actuator and sensor





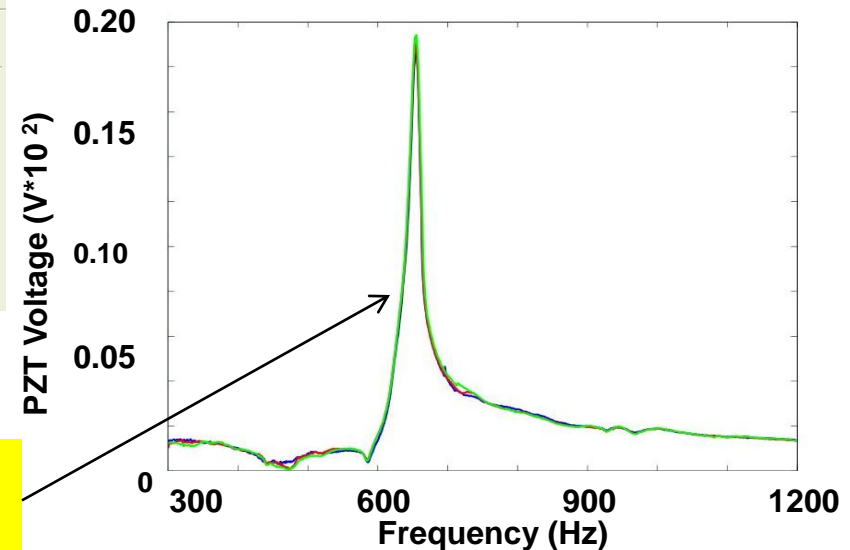
Frequency response of the beams was measured on both Laser Doppler Vibrometer and a shaker table.

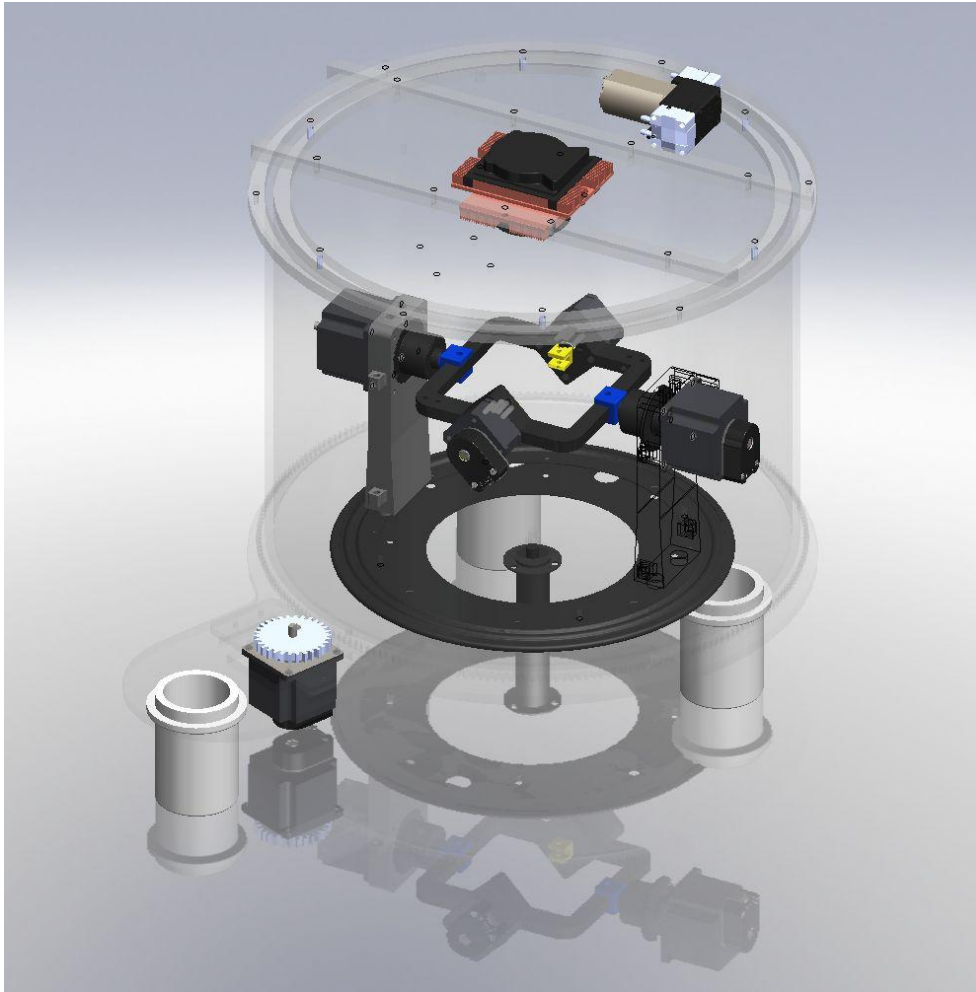


LDV Data

Both show the same fundamental resonance at 648Hz

Amplified (100x) signal on drive PZT actuator when excited by external shaker





- 3-Axis angular rate table, design and fabrication by J. Shumaker (ARL -VTD)
- Haltere circuit is sensitive to
 - Drive Motor Noise
 - Slip Rings
 - Unshielded Wiring
- Initial qualitative results indicate that the sensor element detects rotation
- New circuit pending to quantify rate sensitivity.

PiezoMEMS Thinfilm Ultrasonic Traveling Wave Motors



University of
Maryland



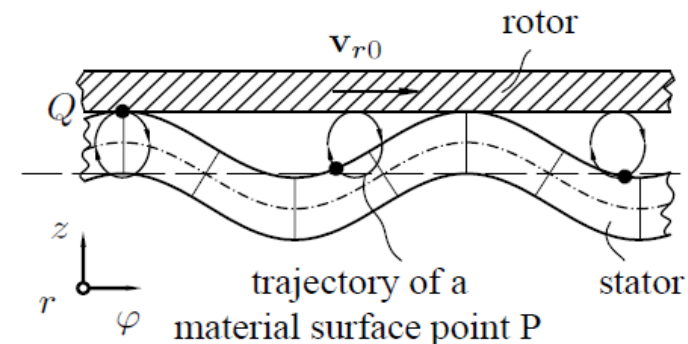
Macro Traveling Wave USM

Advantages:

- High torque at low speed
 - Low power
 - No gearing required
 - Zero backlash
 - Holding torque with zero standby power
 - Compact & few moving parts
 - Unaffected by electromagnetic interference
- Commercially in DSLR camera auto focus lenses
 - Shinsei, K. Uchino, A.V. Carazo et al.

MEMS Thin-Film USM

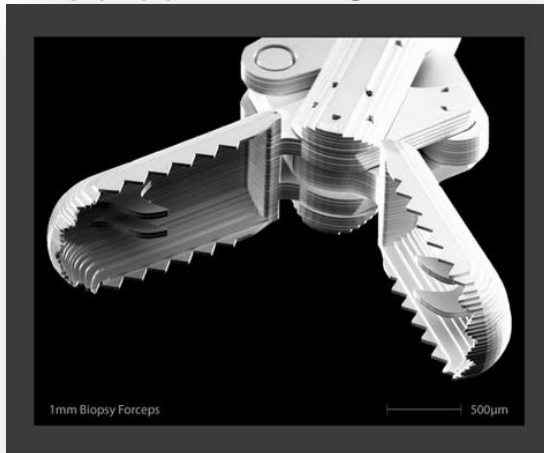
- Reduced size ($<1\text{mm}^3$)
 - Traveling wave style USM previously shown only at $>1\text{cm}$ scale
 - Flat profile-surface mount
- Low voltage operation (0-10V)
- Wafer level fabrication and packaging
 - No assembly required
 - Batch production
 - Lower cost with volume



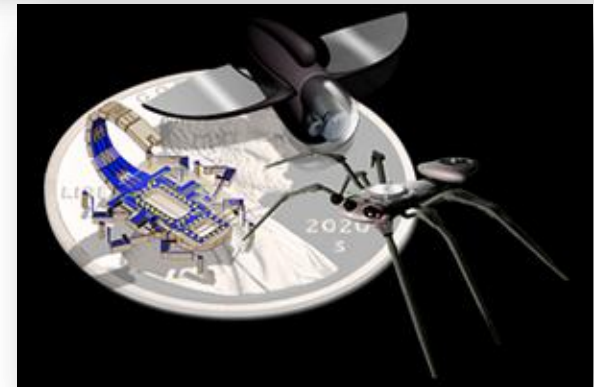
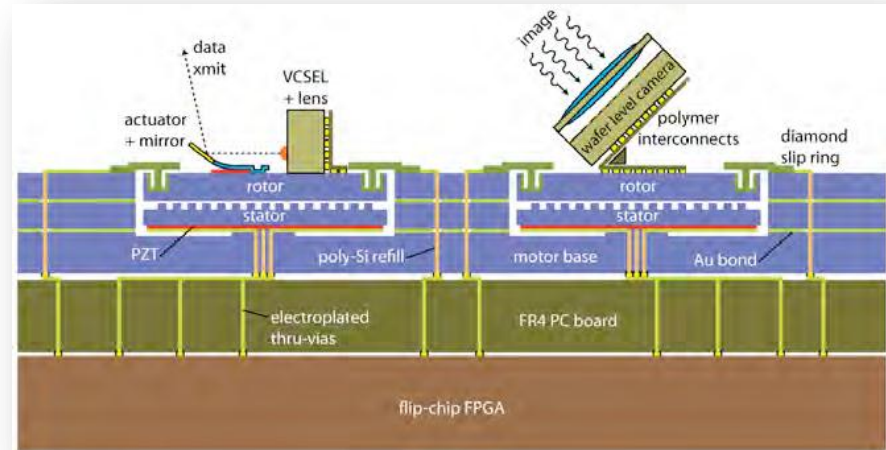
T. Sattel, "Dynamics of Ultrasonic Motors", Doctoral Thesis, Technische Universität Darmstadt, Germany, 2002.

Approved for Public Release

- Small scale robotics
- Steering directional sensors and optical devices
- Information Tethered Micro Automated Rotating Stages (DARPA)
- Medical MEMS



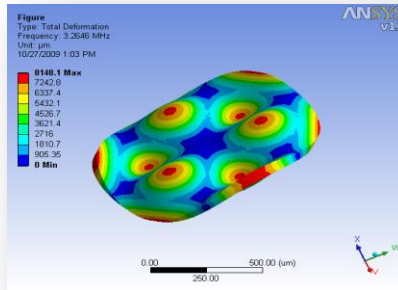
“Microfabrica SEM Image Gallery”, *Microfabrica – MICA Freeform*,
<http://www.microfabrica.com/gallery.html>, accessed
on 7/22/11



“Micro Autonomous Systems and Technology (MAST)”, *Micro Autonomous Systems and Technology (MAST) US Army Research Laboratory*,
<http://www.arl.army.mil/www/default.cfm?page=332>, accessed on 5/26/11

Approved for Public Release

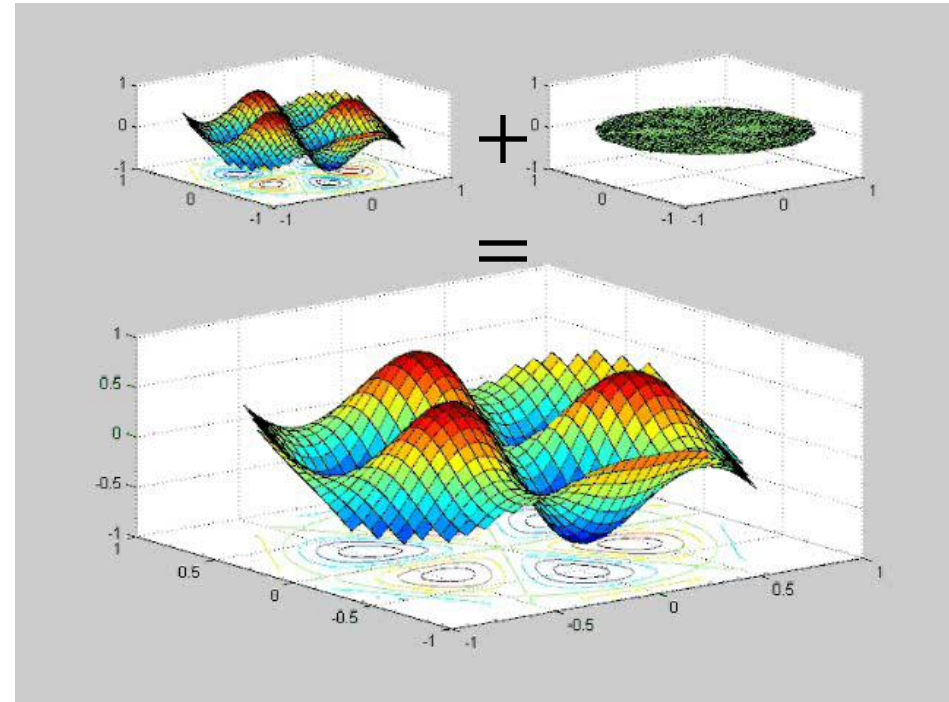
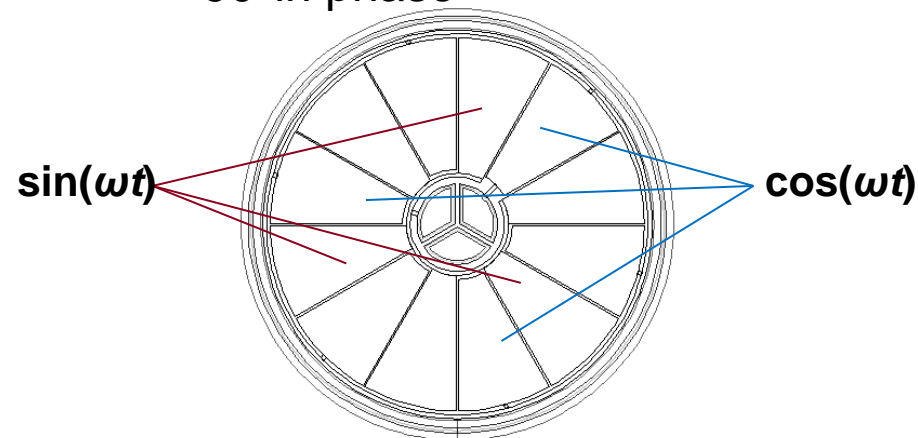
**B₁₃ mode at
250kHz in
3mm stator**



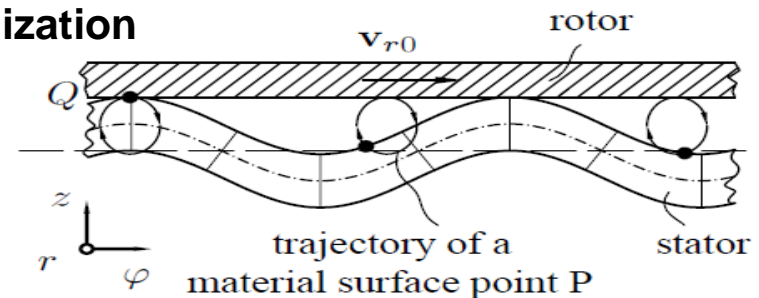
- Combining standing waves apart in space and offset in phase:

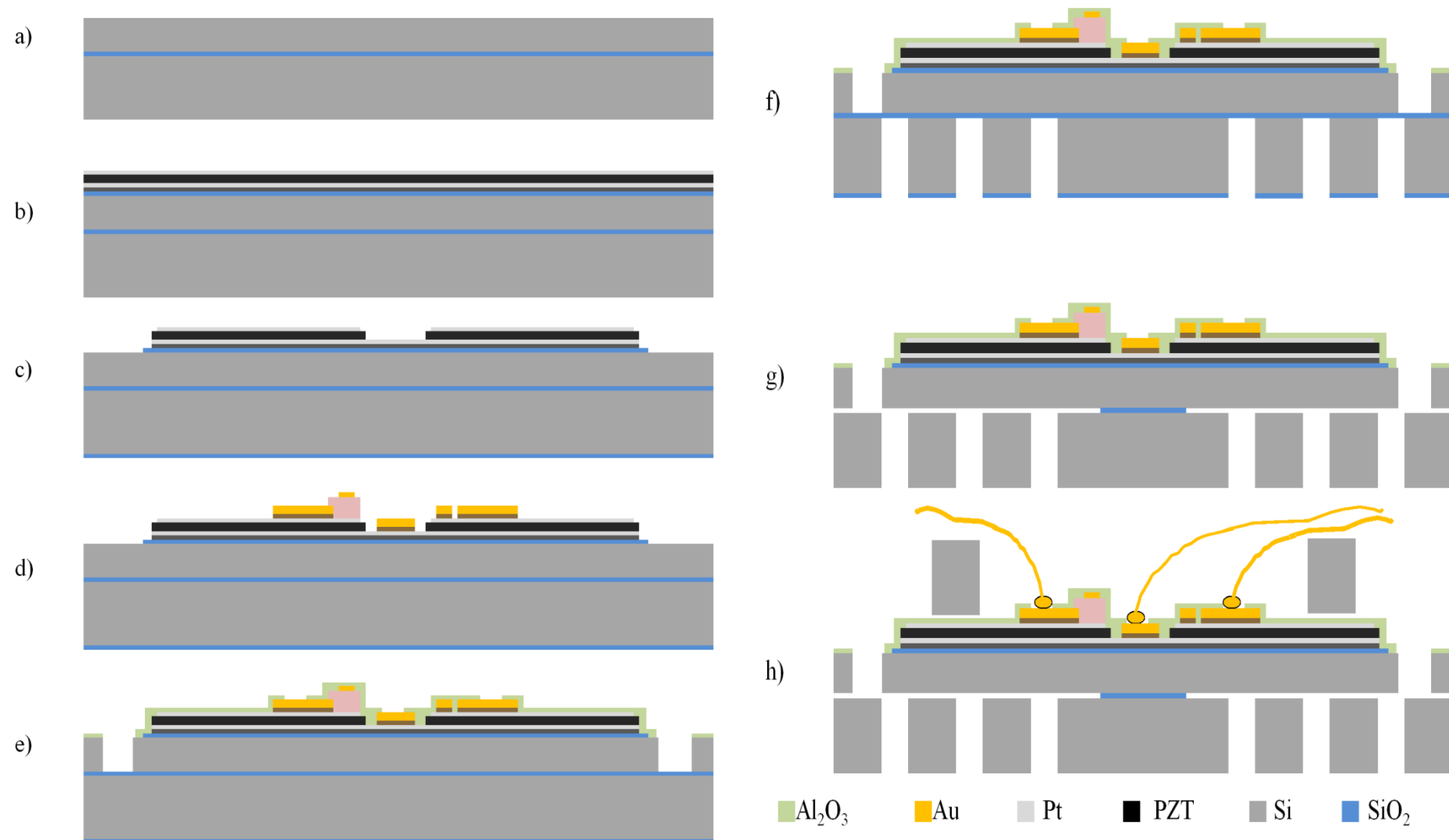
$$\cos(n\theta) \cos(\omega t) + \sin(n\theta) \sin(\omega t) = \cos(n\theta - \omega t)$$

- Electrodes separated by:
 - $\frac{1}{4}$ wavelength in space
 - 90° in phase

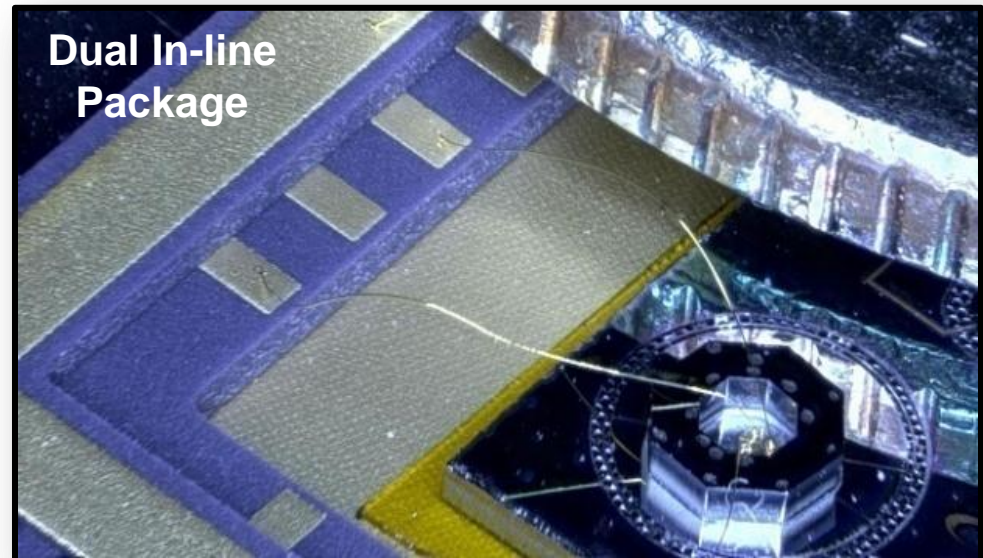
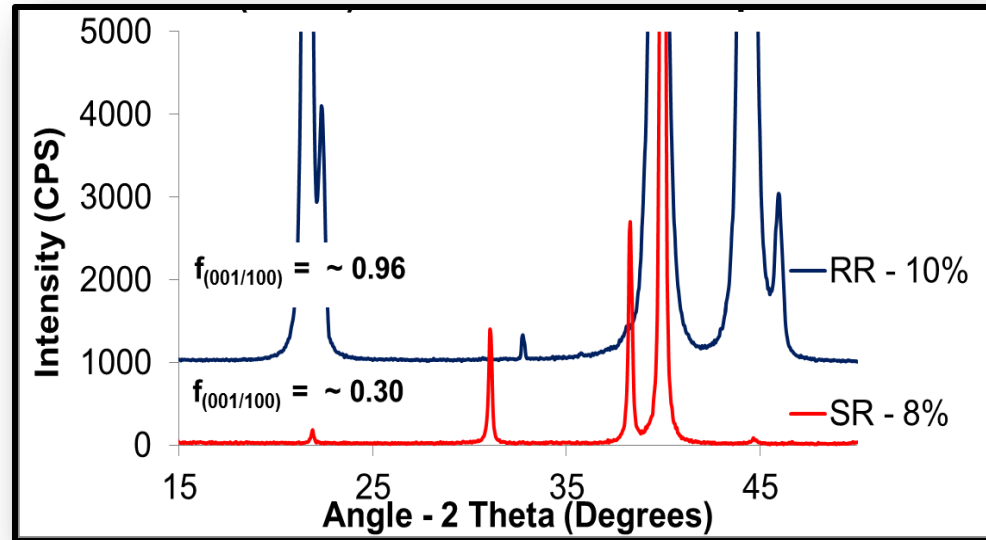


Note: Exaggerated z displacements for visualization



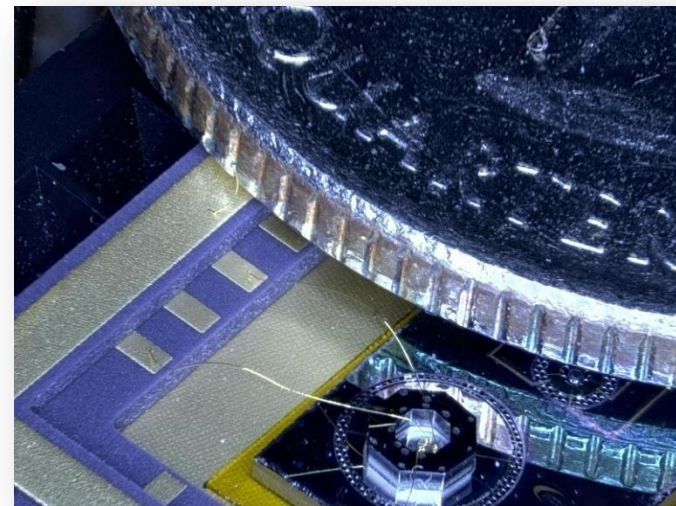


- PZT (52/48) thin films
 - Deposited by chemical solution deposition with 10% Pb excess
 - Pt template (111) with a FWHM of 2 deg
 - (001) PZT with a Lotgering Factor > 0.95
- Pt & PZT Patterning → Ion-mill configured with SIMS endpoint detection
- ALD Al_2O_3 added to provide etch barrier for Vapor HF
- Final Release
 - Backside DRIE of Si
 - Die separation
 - Wirebonding in DIP
 - Vapor HF release of Buried Ox

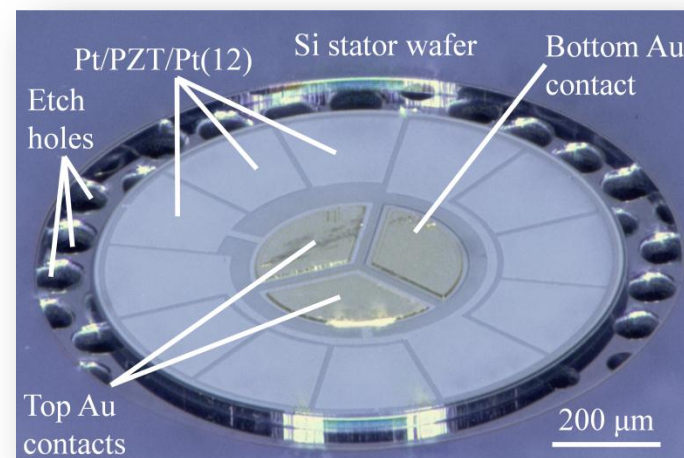


Modeled/Experimental Motor Parameters

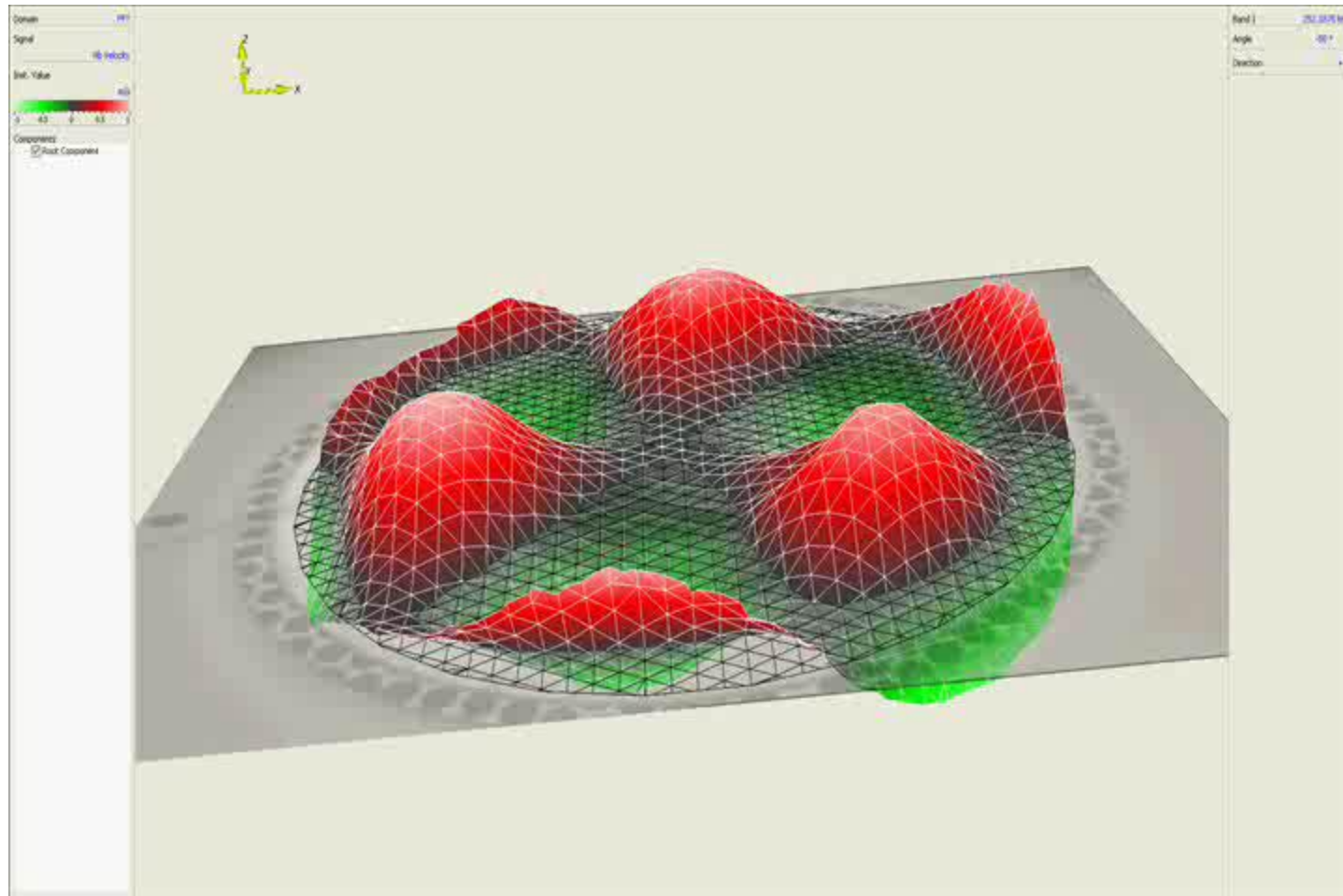
Parameter	Value
Voltage input	0-10V
Stator diameter	0.5 - 3 mm
Stator height	30 μm
PZT thickness	1 μm
Eigenfrequency (B13 mode) 3mm	240 kHz
Max output speed	2400 RPM
Maximum output (stall) torque	3.5 N mm
Input power @ 1 Hz	8 mW



Proof-of-concept motor

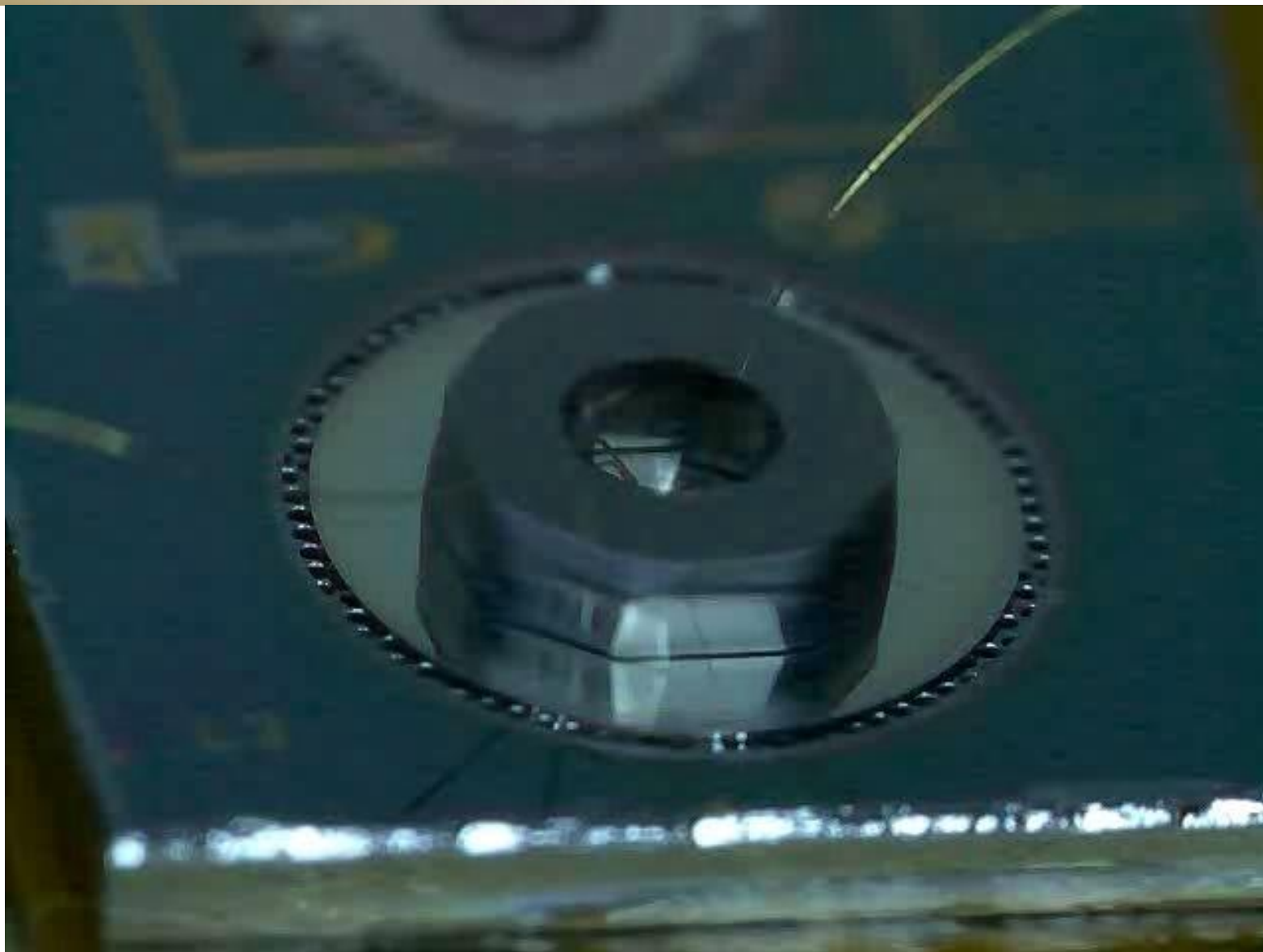


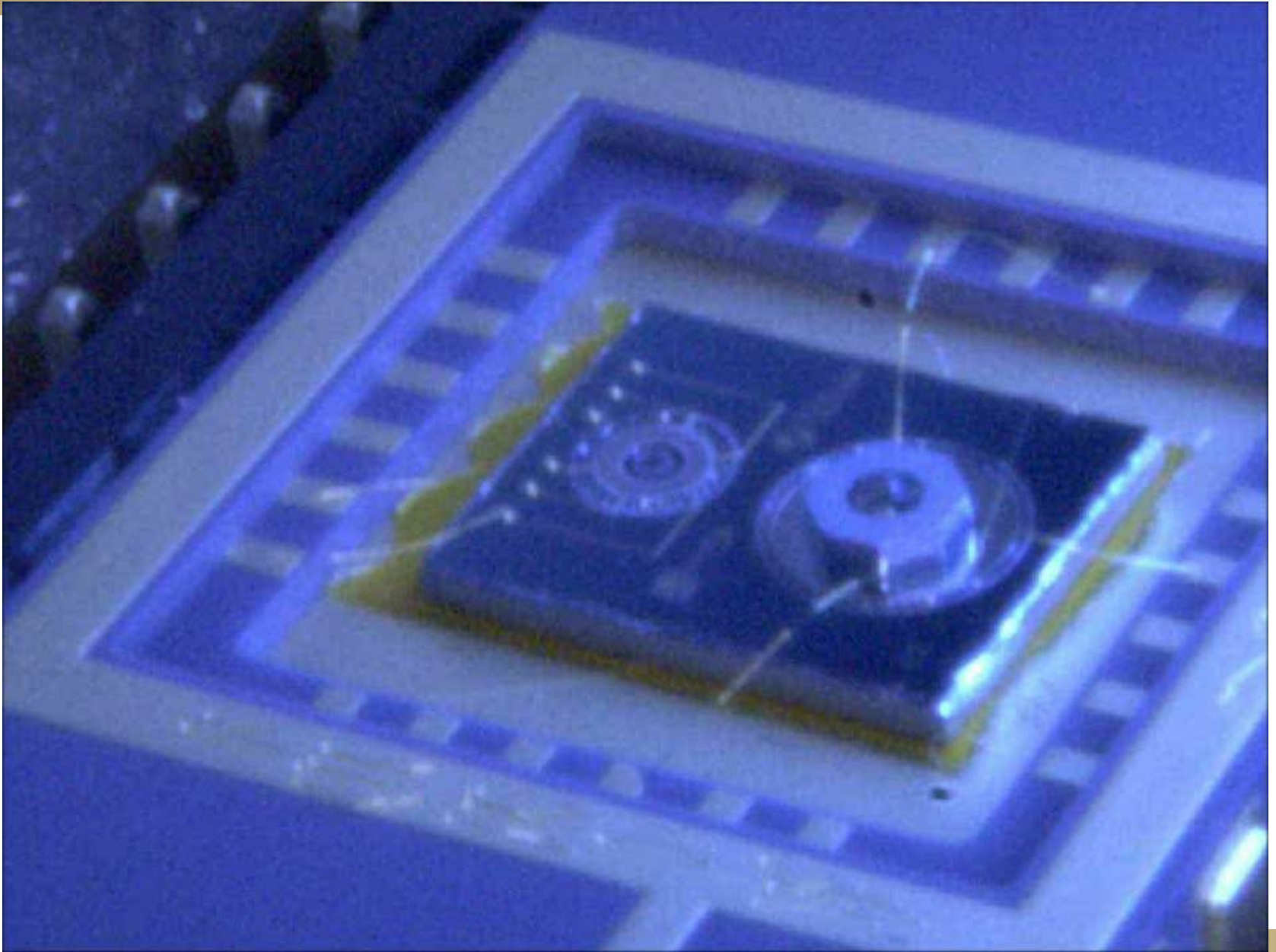
Center fixed stator disc

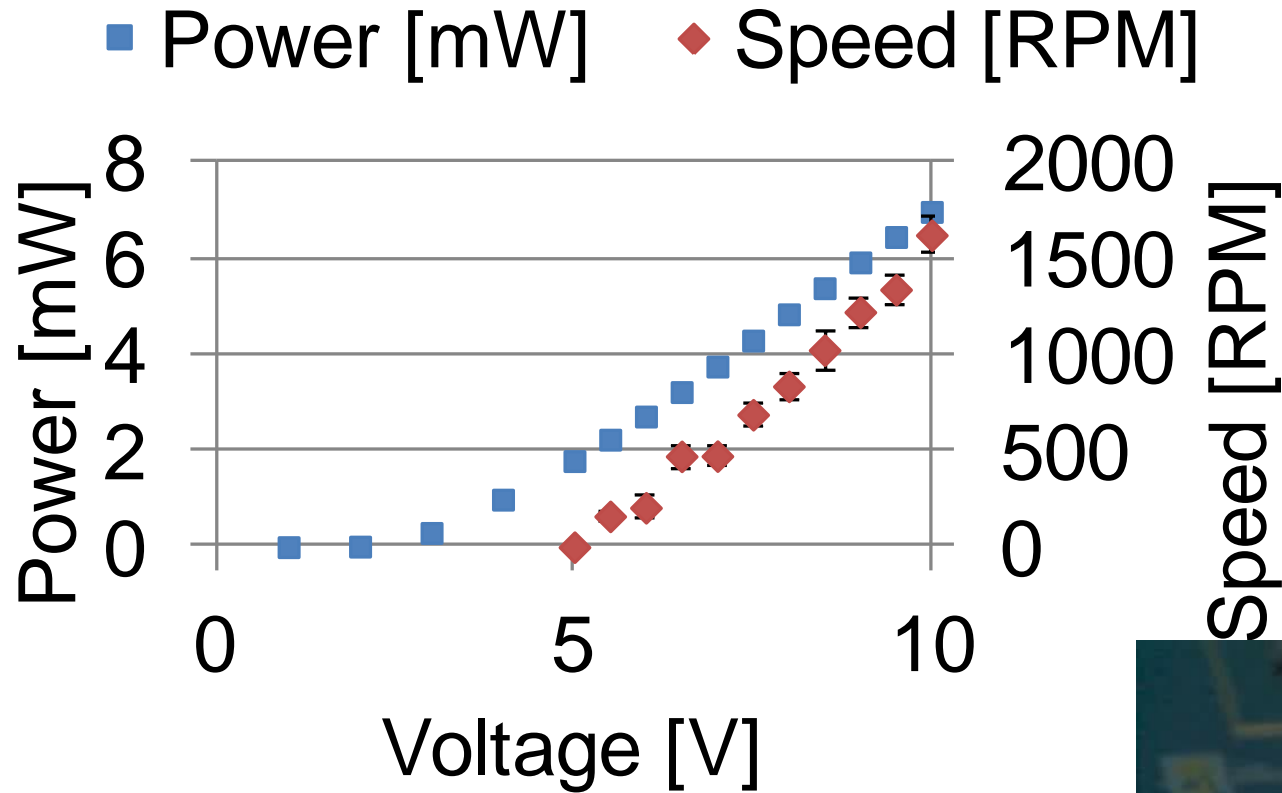


Characterized on a Polytec LDV
Traveling wave peaks travel 80kHz for 3mm stator @ 240kHz
resonant excitation

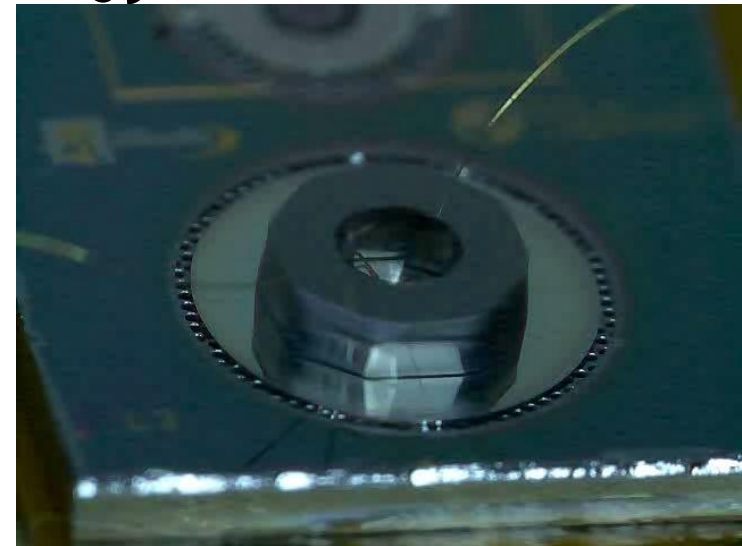
2mm Rotor on 3mm Stator 1000 FPS







- Rotor motion captured using high speed camera
- 2mm rotor on 3 mm stator
- Speed is linear with voltage
- Bi-directional motion with phase change

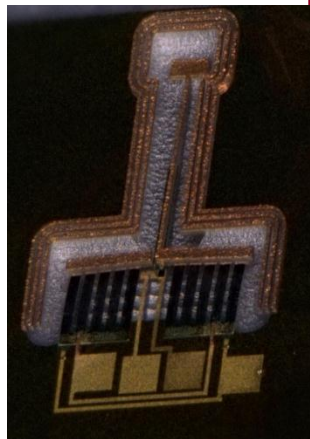


PiezoMEMS Haltere

- PiezoMEMS Haltere was designed to detect angular rate.
- Individual, coupled, and arrayed halteres were fabricated in the MEMS cleanroom at ARL-ALC.
- Drive motion demonstrated.
- Initial materials, composite, and dynamic testing is underway on the completed sensors.

Future work:

- Reduce amplifier noise
- Quantify rate sensitivity on rotating platform.
- Iterate design for greater rate sensitivity.



Approved for Public Release

Traveling Wave Motor

- Proof-of-concept motor demonstrated and characterized
- Traveling wave stator motion measured and characterized
- Motor performance model developed.

Future Work:

- Stator Tooth Integration
 - Electroplating
 - Aerosol jet deposition
- Wafer scale rotor integration and clamping mechanism
- Frictional material characterization
- FPGA control or ASIC

